



NTG

IBF 200



Technical data:

| | |
|-------------------|---|
| Working range: | Ø5mm–Ø200mm Ø0.2 inches –Ø2.75 inches |
| Thickness: | 100mm (4 inches) |
| Weight: | max. 10kg (22 lb.) |
| Contact angle: | max. 63° - standard version max. 90° - type 200-5 |
| Shape: | concave, convex, plane spherical, aspherical, freeform |
| Load lock system: | for two substrates, continuous process |

Number of axes:

| | |
|-------------|--|
| Type: 200-3 | X,Y,Z,A |
| Type: 200-S | X,Y,Z,A,B |
| Travel: | X = 400mm Y = 400mm Z = 400mm A ± 45° B = continuous |

Dimensions:

| | |
|---------------------|--|
| Weight: | 2,450kg (5390 lbs.) |
| Dimensions: (wxhxd) | 3,75m x 2,2m x 1,70m (148 x 87 x 67 inches) |
| Footprint: | 5,75mx3,7m 226 x 146 inches |

Power supply:

| | |
|-------------------------------|---------------------------|
| Mains requirement: volt. | 400V – 3 phases +N+PE |
| Mains requirement.: frequency | 50-60 Hz |
| Current per phase max.: | 32A |
| Power requirement: | max. 22 kW / Average 7 kW |

Utilities supply:

| | |
|-----------------------------|------------------------------|
| Nitrogen: | |
| Pressure: | 1 .. 3 bar g (15..45 psi) |
| Purity: | 99,99 % |
| Argon: | |
| Pressure: | 0.7 .. 1bar g (10.5..15 psi) |
| Purity: | min. 99.9990 % (5.0) |
| Compressed air: | |
| Pressure: | 4..10 bar g (60..150 psi) |
| Quality class to ISO 8573-1 | 2 4 1 |
| Cooling water pressure: | 5 .. 6 bar g (60 .. 90 psi) |
| Cooling water temp.: | 20°C (68°F) |
| Cooling water temp.-stab.: | +/- 0.5°C |
| Vacuum pumps exhaust | pipe DN 40 |



The IBF-200 is a plant for nanometer exact correction of small to medium sized optical surfaces. In the 200-S configuration it is possible to process substrates with a contact angle up to 90°. Beside this direct Ion beam smoothing and reactive etching can be performed on this plant too. This makes it most interesting for institutes and universities.

www.ntg.de